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| FORM PTO-1449 (Modified)<br><br>INFORMATION DISCLOSURE CITATION<br>IN AN APPLICATION<br><br>(Use several sheets if necessary) | Docket No. 01SC062US2                | Application Number |
|   | Applicants: James Chingwei Li, et al |                    |
|   | Filing Date                          | Group Art Unit     |

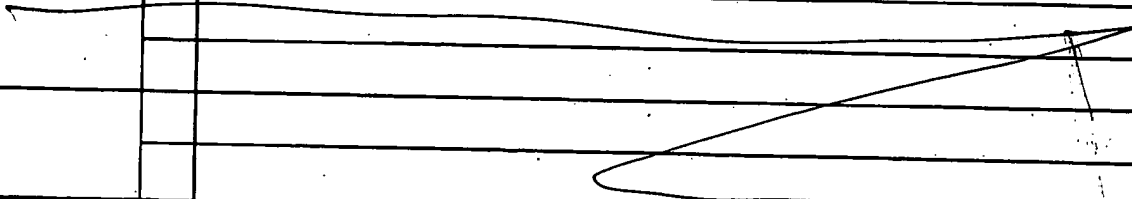
## U.S. PATENT DOCUMENTS

[illegible]

## FOREIGN PATENT DOCUMENTS

[illegible]

| OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.) |  |   |  |
|--|--|---|--|
|  |  | F. C. Colson, R. L. Bates, M. F. Bishop, et al. |  |

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| ✓✓<br>E. G. Colgan, R.J. Polastre, M. Takeichi and R.L. Wisnieff, <u>Thin-Film-Transistor Process-Characterization Test Structures</u> , February 12, 1998, <a href="http://www.research.ibm.com/journal/rd/423/polastre.txt">http://www.research.ibm.com/journal/rd/423/polastre.txt</a> |                             |
|   |                             |
| Examiner<br>✓ J. G. S. V. K.  | Date Considered<br>06/23/04 |
| EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.  |                             |